



Attorney Docket: 081468-0306781  
Client Reference: P-0381.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:  
JOERI LOF ET AL.

Confirmation Number: 5288

Application No.: 10/705,805

Group Art Unit: 2851

Filed: November 12, 2003

Examiner: Peter B. Kim.

Title: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

**REQUEST FOR RETURN OF PTO-1449**

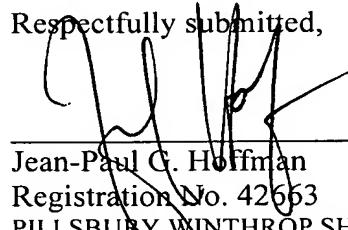
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

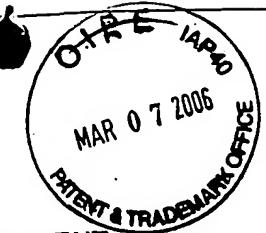
Applicants respectfully request that the Examiner return an initialed copy of the PTO-1449 form that was filed on November 12, 2003. A copy of the PTO-1449 and stamped USPTO receipt are attached for the Examiner's convenience.

Applicants respectfully request that the Examiner initial, sign and date the references on the attached PTO-1449 form dated November 12, 2003, and return the form to the undersigned.

Respectfully submitted,

  
Jean-Paul G. Hoffman  
Registration No. 42663  
PILLSBURY WINTHROP SHAW PITTMAN LLP  
P.O. Box 10500  
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Customer No. 00909

Date: March 7, 2006



Atty.  
 Dkt. No.

M#

Client Ref.

306781

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Applicant: Joeri LOF et al.

Appln. No.: Unknown

Filing Date: November 12, 2003

Examiner: Unknown Group Art Unit: Unknown

Date: November 12, 2003

Page 1 of 3

### INFORMATION DISCLOSURE STATEMENT BY APPLICANT

U.S. PATENT DOCUMENTS									
Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)			
AR	3,573,975	04/1971	Dhaka et al.	117	212				
BR	3,648,587	03/1972	Stevens	95	44				
CR	4,346,164	08/1982	Tabarelli et al.	430	311				
DR	4,396,705	08/1983	Akeyama et al.	430	326				
ER	4,480,910	11/1984	Takanashi et al.	355	30				
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GR	5,040,020	08/1991	Rauschenbach et al.	355	53				
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LR	5,900,354	05/1999	Batchelder	430	395				
MR	6,191,429	02/2001	Suwa	250	548				
NR	6,560,032	05/2003	Hatano	359	656				
FOREIGN PATENT DOCUMENTS						English Abstract	Translation Readily Available		
	Document Number	Date MM/YYYY	Country	Inventor Name		Enclosed	No	Enclose	No
OR	WO 99/49504	09/1999	PCT	Fukami et al.		X		X	
PR	EP 0023231	02/1981	Europe	Tabarelli et al.		X			
QR	EP 0418427	03/1991	Europe	Miyake		X		X	
RR	EP 1039511	09/2000	Europe	Murakimi et al.		X		X	
SR	DD 224448	07/1985	German	Hesse et al.				X	
TR	DD 242880	02/1987	German	Kuch				X	
UR	FR 2474708	07/1981	France	Letellier				X	
VR	JP 62-065326	03/1987	Japan	Moriuchi		X			
WR	JP 62-121417	06/1987	Japan	Nakazawa		X			
XR	JP 63-157419	06/1988	Japan	Nakasuij		X			
OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)									
YR	EP Search Report for EP 02257938 dated September 25, 2003								
ZR	M. Switkes et al., "Immersion Lithography at 157 nm", MIT Lincoln Lab, Orlando 2001-1, December 17, 2001								
AAR	M. Switkes et al., "Immersion Lithography at 157 nm", J. Vac. Sci. Technol. B., Vol. 19, No. 6, November/December 2001, pp. 2353-2356								
BBR	M. Switkes et al., "Immersion Lithography: Optics for the 50 nm Node", 157 Anvers-1, September 4, 2002								

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

FORM PTO-1449 (modified)  
To: U.S. Department of Commerce  
(PW FORM PAT-1449)  
Patent and Trademark Office



Atty. Dkt. No.	M#	Client Ref.
	306781	P-0381.010-US

Applicant: Joeri LOF et al.

Appln. No.: Unknown

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Examiner: Unknown Group Art Unit: Unknown

**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**

Date: November 12, 2003

Page 2 of 3

**U.S. PATENT DOCUMENTS**

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
CCR	6,603,130	08/2003	Bisschops et al.	250	492.1	
DDR	6,633,365	10/2003	Suenaga	355	53	
EER	2002/0163629	11/2002	Switkes et al.	355	53	
FFR	2003/0123040	07/2003	Almogy	355	69	
GGR	2003/0174408	09/2003	Rostalski et al.	359	642	
HHR						
IIR						
JJR						
KKR						
LLR						
MMR						
NNR						
OOR						
PPR						

**FOREIGN PATENT DOCUMENTS**

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
QQR	JP 04-305915	10/1992	Japan	Ozeki et al.		X		
RRR	JP 04-305917	10/1992	Japan	Ozeki et al.		X		
SSR	JP 06-124873	05/1994	Japan	Takahashi		X		X
TTR	JP 07-220990	08/1995	Japan	Fukuda et al.		X		
UUR	JP 10-228661	08/1998	Japan	Kurokawa		X		
VVR	JP 10-255319	09/1998	Japan	Suenaga et al.		X		
WWR	JP 10-303114	11/1998	Japan	Suwa		X		
XXR	JP 10-340846	12/1998	Japan	Kudo		X		X
YYR	JP 2001-091849	04/2001	Japan	Aizaki et al.		X		
ZZR								

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

AAAR	B.J. Lin, "Drivers, Prospects and Challenges for Immersion Lithography", TSMC, Inc., September 2002		
BBBR	B.J. Lin, "Proximity Printing Through Liquid", IBM Technical Disclosure Bulletin, Vol.20, No. 11B, April 1978, p. 4997		

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CCC										
DDD										
EEE										
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FFFF										
GGG										
OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)										
HHH	B.J. Lin, "The Paths To Subhalf-Micrometer Optical Lithography", SPIE Vol. 922, Optical/Laser Microlithography (1988), pp. 256-269									
IIIR	G.W.W. Stevens, "Reduction of Waste Resulting from Mask Defects", Solid State Technology, August 1978, Vol.21 008, pp. 68-72									
JJJR	S. Owa et al., "Immersion Lithography; its potential performance and issues", SPIE Microlithography 2003, 5040-186, February 27, 2003									
KKK	S. Owa et al., "Advantage and Feasibility of Immersion Lithography", Proc. SPIE 5040 (2003)									
LLL	Nikon Precision Europe GmbH, "Investor Relations – Nikon's Real Solutions", May 15, 2003									
MM	H. Kawata et al., "Optical Projection Lithography using Lenses with Numerical Apertures Greater than Unity", Microelectronic Engineering 9 (1989), pp. 31-36									
NNN	J.A. Hoffnagle et al., "Liquid Immersion Deep-Ultraviolet Interferometric Lithography", J. Vac. Sci. Technol. B., Vol. 17, No. 6, November/December 1999, pp. 3306-3309									
OOO	B.W. Smith et al., "Immersion Optical Lithography at 193nm", FUTURE FAB International, Vol. 15, July 11, 2003									
PPP	H. Kawata et al., "Fabrication of 0.2μm Fine Patterns Using Optical Projection Lithography with an Oil Immersion Lens", Jpn. J. Appl. Phys. Vol. 31 (1992), pp. 4174-4177									
QQQ	G. Owen et al., "1/8μm Optical Lithography", J. Vac. Sci. Technol. B., Vol. 10, No. 6, November/December 1992, pp. 3032-3036									
RRR										
SSS										
TTT										
UUU										
VVV										
WW										
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YYY										

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PTO RECEIPT Attorney Docket: 081468-0306781

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Atty: Jack Barufka/JPH:K.S. Hines

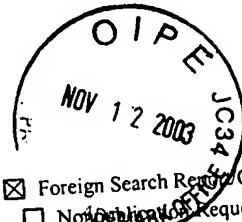
Appln. No: 1,000 Date: November 12, 2003

Inventor(s): Joeri LOF et al.

Title: LITHOGRAPHIC APPARATUS AND DEVICE

MANUFACTURING METHOD

Preliminary Amendment  Application Data Sheet  
 Appendix  Utility/Design/Provisional  
 19 No. of Pages Application (Spec + Claim(s) + Abstract)  
 No. of Pages Separate Power of Attorney  
 47 No. of Numbered Claims Only  
 Declaration (of pages)  
 Assignment  Cover Sheet  
 1 No. of Priority Documents  
 2 No. of Sheets of Drawings (Fig(s) 1-4)  Foreign Search Report/OA  
 IDS  Appendix for Cited Appl(s)  Nonpublication Request  
 PTO-1449  Cited Documents  
S Total Fee Charged to Deposit Account 033975



Other: Submission of Priority Document  
CURRENT DUE DATE:

DATE \_\_\_\_\_

CDC-285A 7/96

PTO RECEIPT Attorney Docket: 081468-0306781

Atty: Jack Barufka/JPH:K.S. Hines

Appln. No: 1,000 Date: November 12, 2003

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 IDS  Appendix for Cited Appl(s)  Nonpublication Request  
 PTO-1449  Cited Documents  
S Total Fee Charged to Deposit Account 033975

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10/705805



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